



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

Serial No.: 10/800,219)
Filed: March 12, 2004)
Title: Method and Apparatus for Verifying)
the Post-Optical Proximity Corrected)
Mask Wafer Image Sensitivity to)
Reticle Manufacturing Errors)
Inventors: Nadya G. Strelkova et al.)
Art Unit: 2825)
Examiner: Nelson C. Lam)
Atty. Ref: 02-2396)

CERTIFICATE OF MAILING

I hereby certify that this paper is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on October 2, 2006.

James R. Foley
James R. Foley, Reg. No. 89,079

*Entered w/fee
4/24/07
and
8/7/07*

RESPONSE TO THE OFFICE ACTION MAILED JULY 31, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In the matter of the above-identified application and in response to the Office Action mailed July 31, 2006, kindly enter the following amendments and consider the following remarks toward reconsideration of the present application.

*Not
Entered
11/15/06*